POLISHING PAD CONDITIONING

ABSTRACT

A rotating polishing wheel (15) having secured to its top surface a polishing pad (13) and a vertically movable carrier element (18) for carrying a workpiece to be polished into contact with the polishing pad (13) and exerting a desired pressure on the workpiece. Operatively attached to the carrier (18) is a conditioning element (24) movable with the carrier (18) and having on its bottom surface cutting means (30) disposed in a circular configuration for conditioning the polishing pad (13) by contact therewith.

FIG. 1